



SENTECH Senduro 300 SN 33/011 Vintage 2008

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The SENDURO® 300 is a powerful automated tool for the measurement of single films and layer stacks on silicon wafers of up to 300 mm diameter.

Highlights and Advantages Measurement recipes (one-click applications) Starting with SENTECH's predefined recipe library the user quickly selects the desired measurement task and executes the complete sequence at once:

- automated alignment,
- data acquisition
- sample modeling
- analysis of single or multi-layer samples by fitting the model to the measured data
- display of results
- reporting of measured data





